

Listing of Claims

This listing replaces all prior versions and listings of claims in the application:

Claim 1 (canceled)

2. (previously presented) The material processing system as claimed in claim 24, wherein the first RF signal and a second RF signal are at different frequencies.

3. (previously presented) The material processing system as claimed in claim 24, wherein the first RF signal and a second RF signal are at the same frequency.

Claim 4 (canceled)

5. (currently amended) The material processing system as claimed in claim 24, further comprising:

an RF bias source configured to provide an RF bias signal; and

an RF subsystem coupled to the process chamber, coupled to the RF bias source and coupled to the ~~test signal~~ RF energy source, wherein the RF subsystem comprises means for combining the first ~~test RF~~ signal, the second ~~test RF~~ signal, and the RF bias signal and means for providing the first ~~test RF~~ signal, the second ~~test RF~~ signal, and the RF bias signal to the process chamber.

6. (currently amended) The material processing system as claimed in claim 5, wherein the RF bias signal ~~is used to generate~~ generates plasma and the first RF signal and the second RF signal are not harmonically related to the frequency of the RF bias signal.

7. (previously presented) The material processing system as claimed in claim 24, wherein the filter/detector comprises an antenna coupled to the process chamber, a filter

coupled to the antenna, and detector coupled to the filter, wherein the filter comprises a bandpass filter (BPF) configured to pass at least one intermodulation product of the first RF signal and the second RF signal.

8. (previously presented) The material processing system as claimed in claim **7**, wherein the at least one intermodulation product of the first RF signal and the second RF signal comprises an odd-order product.

9. (previously presented) The material processing system as claimed in claim **8**, wherein the at least one intermodulation product of the first RF signal and the second RF signal comprises a fifth order product.

10. (previously presented) The material processing system as claimed in claim **8**, wherein the at least one intermodulation product of the first RF signal and the second RF signal comprises a seventh order product.

11. (currently amended) The material processing system as claimed in claim **7**, wherein the filter/detector further comprises a power source coupled to at least one of the antenna, a filter, and a detector.

12. (original) The material processing system as claimed in claim **11**, wherein the power source comprises at least one of an RF-to-DC converter configured to convert energy emitted from a process related signal into a DC signal, an RF-to-DC converter configured to convert a non-process related signal into a DC signal, a DC-to-DC converter, and a battery.

13. (previously presented) The material processing system as claimed in claim **7**, wherein the filter/detector further comprises a controller coupled to at least one of the antenna, filter, and detector.

14. (original) The material processing system as claimed in claim **13**, wherein the controller comprises at least one of a microprocessor, a microcontroller, a timer, digital signal processor (DSP), memory, receiver, A/D converter, and D/A converter

15. (currently amended) The material processing system as claimed in claim **24**, wherein:

the ~~test signal~~ RF energy source further comprises comprising:

- a first source providing a ~~the~~ first RF signal at least one frequency;
- a second source providing a ~~the~~ second RF signal at least one frequency;
- a summing circuit for combining the first RF signal and the second RF signal;
- an isolation amplifier coupled to the summing circuit for amplifying the first RF signal and the second RF signal; and
- an antenna coupled to the isolation amplifier for transmitting the first RF signal and the second RF signal into the process chamber.

16. (original) The material processing system as claimed in claim **15**, wherein the first source and the second source comprise sine wave oscillators.

17. (currently amended) The material processing system as claimed in claim **7**, wherein the RF energy source ~~source~~ further comprises a power source coupled to at least one of the antenna, the filter, and the detector.

18. (original) The material processing system as claimed in claim **17**, wherein the power source comprises at least one of an RF-to-DC converter configured to convert energy emitted from a process related signal into a DC signal, an RF-to-DC converter configured to convert a non-process related signal into a DC signal, a DC-to-DC converter, and a battery.

19. (currently amended) The material processing system as claimed in claim **7**, wherein the RF energy source further comprises a controller coupled to at least one of the antenna, the filter, and the detector.

20. (original) The material processing system as claimed in claim **19**, wherein the controller comprises at least one of a microprocessor, a microcontroller, a timer, digital signal processor (DSP), memory, receiver, A/D converter, and D/A converter

Claims **21-23** (canceled)

24. (currently amended) A material processing system comprising:
a processing tool having at least one process chamber;
at least one RF energy source coupled to the process chamber, the source providing a first RF signal and a second RF signal in the process chamber, ~~which signals will that produce an intermodulation product if and when plasma is present in the process chamber;~~
a filter/detector for detecting an intermodulation product of the first RF signal and the second RF signal in the process chamber; and
a controller coupled to the filter/detector and the processing tool, the controller comprising means for determining that a plasma is present in the chamber in response to detection of an intermodulation product and for determining that a plasma is absent from

the chamber in absence of the detection of an intermodulation product, and for controlling the processing tool in response to the determinations.

25. (previously presented) The material processing system as claimed in claim **24**, wherein the RF energy source includes a first signal source for providing the first RF signal, a second signal source for providing the second RF signal, a summing circuit for combining the first RF signal and the second RF signal, an isolation amplifier for amplifying the first RF signal and the second RF signal, and an antenna coupled to the process chamber for transmitting the first RF signal and the second RF signal to the process chamber.